

ABAQUS [20]. The FEA model assumes symmetry about the central axis along the length of the copper interconnect and hence only 1 cell and half of the interconnect was modeled as shown. In order to make the model computationally inexpensive, intricate geometric details (ref. Fig. 3) of the copper interconnect were omitted and solder joint was idealized to be under the interconnect tab as shown in Fig. 2. Back metallization of the cell (ref. Fig. 3) was not considered due associated modeling difficulties and unavailability of the geometric parameters. Its effect was assumed to be the same in all the cases studied in this manuscript. The model was meshed with 8 node linear quadrilateral elements of area $\sim 0.3 \text{ mm}^2$ around the solder joint and the cell thickness ($180 \text{ }\mu\text{m}$) was divided into 6 layers as shown to capture local high stresses in the c-Si cell. Anisotropy of the silicon elasticity was considered as given by Eqn (1) [21] and the elastic material properties of the cell, interconnect and solder, given in Table 1 [9-10, 22] was used in the analysis.

Elasticity tensor of c-Si $\langle 100 \rangle$ in GPa,

$$c = \begin{bmatrix} 166 & 64 & 64 & 0 & 0 & 0 \\ 64 & 166 & 64 & 0 & 0 & 0 \\ 64 & 64 & 166 & 0 & 0 & 0 \\ 0 & 0 & 0 & 80 & 0 & 0 \\ 0 & 0 & 0 & 0 & 80 & 0 \\ 0 & 0 & 0 & 0 & 0 & 80 \end{bmatrix} \quad (1)$$

Elastic-plastic behavior of the interconnect and solder was also considered in this analysis and the respective plastic properties were given in Table 2 [10, 23]. The model was constrained at the bottom most node of the cell below the middle solder joint to arrest rigid body motion. The CTE mismatch was simulated by steady state response of the model upon cooling from uniform soldering temperature of $210 \text{ }^\circ\text{C}$ to room temperature, $25 \text{ }^\circ\text{C}$.

Table 1. Elastic Material Properties [9-10, 22]

Material	Young's Modulus, E		Poisson's Ratio	CTE (mm/mm/deg C)	
	Value	Temperature (deg C)		Value (PPM)	Temperature (deg C)
Silicon	Eqn (1)	---	0.28	1.72	-53
				2.23	-13
				2.61	27
				2.92	67
				3.34	147
Copper (Interconnect)	91.5	-40	0.3	17	---
	85.7	25			
	82	125			
	79.2	225			
Solder (Sn-Ag-Cu)	53	0	0.35	21	---
	45	100			
	36	200			

Table 2. Plastic Material Properties [10, 23]

Material	Yield Stress (MPa)	Tangent Modulus (MPa)	Temperature (deg C)
Copper (Interconnect)	116.2	1000	-40
	95.1	1000	25
	82	1000	125
	79.2	1000	225
Solder (Sn-Ag-Cu)	45	-	25
	28	-	180
	25	-	210

3 Experimental

Changes in crystal orientation of the solar cell sample of nominal thickness ($\sim 180 \text{ }\mu\text{m}$) as shown in Fig. 3 were measured with μSXR D on beamline 12.3.2 of the Advanced Light Source, Berkeley, CA. The experimental procedure was discussed elsewhere [13-14]. Further details on μSXR D technique, Synchrotron X-ray beam and data analysis can be obtained from references [15-19]. From the data analysis of μSXR D scan [18], the mis-orientation angles (φ_x, φ_y) of the c-Si wafer with respect to the undeformed wafer mid plane (XY plane) were obtained. Then curvatures of the wafer (κ_{xx}, κ_{yy}) with respect to X and Y-axes can be calculated using Equations (2) and (3).

$$\kappa_{xx} = -\left. \frac{\partial \varphi_y}{\partial x} \right|_{y=\text{const}}, \varphi_y \text{ in radians} \quad (2)$$

$$\kappa_{yy} = -\left. \frac{\partial \varphi_x}{\partial y} \right|_{x=\text{const}}, \varphi_x \text{ in radians} \quad (3)$$

Using assumptions similar to Kirchhoff plate model [23], the bending strains of the silicon cell can be calculated from curvatures by Equations (4) and (5).

$$\epsilon_{xx} = -\frac{t}{2} \kappa_{xx}, 't' \text{ is thickness of the c-Si cell} \quad (4)$$

$$\epsilon_{yy} = -\frac{t}{2} \kappa_{yy} \quad (5)$$

Since the silicon cell is very thin, assuming the through thickness normal stress (σ_{zz}) to be zero let us calculate the cell bending stresses (σ_{xx}, σ_{yy}) using Hooke's law. The results were presented in the following sections.

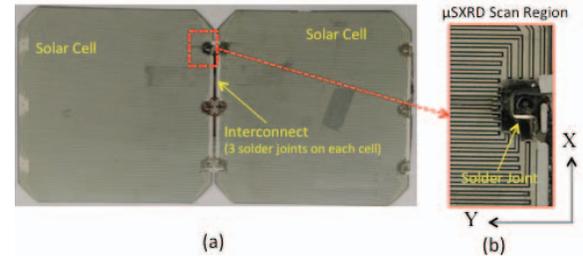


Fig. 3. (a) Experimental sample of the soldered cells, (b) μSXR D scan region

4 Results & Discussion

In this manuscript the primary focus is on the residual stresses induced by soldering process and the solder joints indeed act as the stress concentration zones, so we limit our discussion of results to the solder joint. Stress contours in the $180 \text{ }\mu\text{m}$ thick c-Si cell surrounding the solder joint considering both elastic and elastic-plastic material properties are shown in Fig. 4. It can be noted that the stresses are concentrating around the solder joint and high in-plane stresses are seen with elastic material properties which reduced significantly upon using elastic-plastic material properties for copper interconnect and solder. The maximum X-direction stress with elastic properties was 176 MPa , which reduced to 133 MPa upon incorporating copper interconnect plasticity and further reduced to 81 MPa upon incorporating solder material plasticity. The reduction of stress is very significant ($>50\%$) and can't be ignored. Similarly the Y-direction stress reduced from 99 MPa to 69 MPa ($>30\%$ reduction). Fig. 5 shows the

experimental stress maps of 180 μm thick back contact mono crystalline silicon cell obtained by μSXR D. The FEA stress contours with elastic plastic material properties (Fig. 4c) compare well with these experimental stress maps, which validates our FEA model. These results also show that the plasticity (or ductility) of the interconnect and solder play crucial role in reducing soldering induced stresses. An alloy material, which is less stiff and more ductile, compared to copper may be a better choice for interconnection to reduce stresses. Or it may be even better to engineer such material.

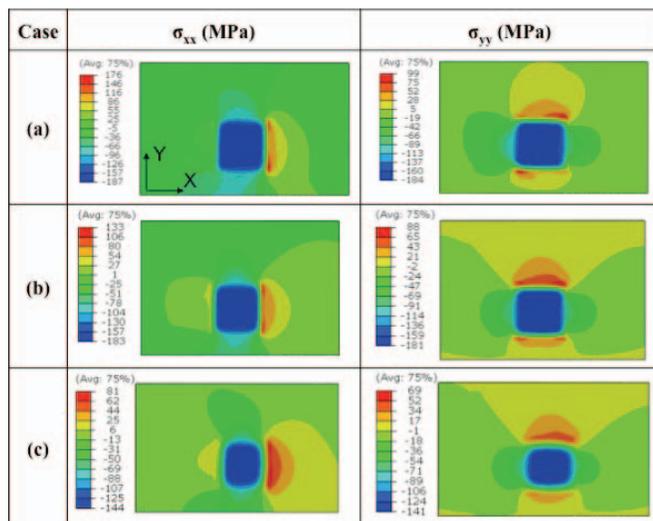


Fig. 4. Post soldering residual stresses of 180 μm thick silicon cell from FEA simulations, (a) with Elastic material properties, (b) with elastic-plastic copper interconnect and elastic solder, (c) with elastic-plastic copper interconnect and solder

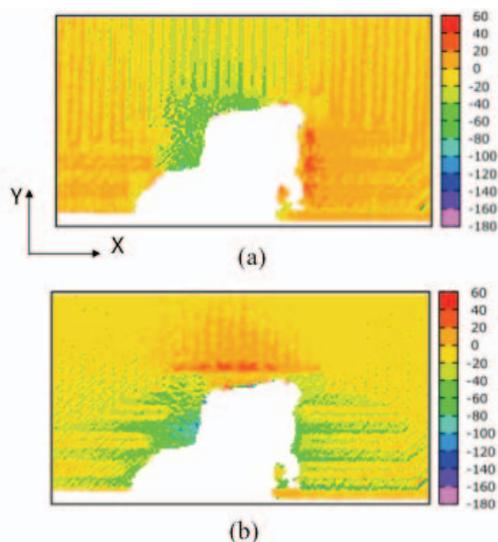


Fig. 5. Post soldering residual stresses of 180 μm thick silicon cell from μSXR D, (a) X-direction stress, (b) Y-direction stress

Further the effect of silicon cell and interconnect thickness on the cell residual stress was simulated (Fig. 6). It can be seen from Fig. 6a that the X-direction stress is increasing almost linearly with reduction in cell thickness and the Y-

direction stress is reducing, which in turn increases the in plane max principal stress, hence tendency to fracture. However decreasing the copper interconnects thickness can counterbalance the reduction in cell thickness. It can be seen from Fig. 6b that the stresses reduce due to reduction interconnect thickness. Similarly the thickness of the solder may also affect the residual stresses, which was not studied in this manuscript.

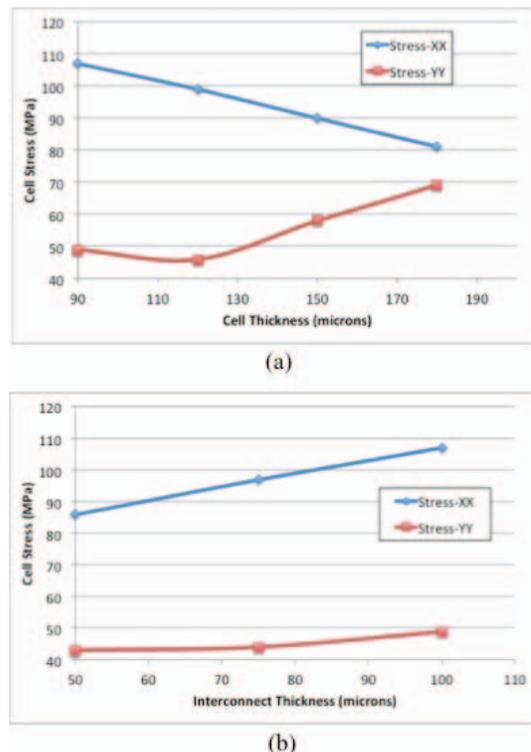


Fig. 6. Post soldering residual stresses of silicon cell from FEA simulations considering elastic-plastic material properties for interconnect and solder, (a) for varying cell thickness, (b) for varying interconnect thickness (cell thickness 90 μm)

Conclusions

The effects of copper interconnect and solder plasticity on the silicon cell residual stresses were simulated using FEA. The residual stress depends significantly on the interconnect plasticity and hence a less stiff and ductile alloy may become a better choice for solar cell interconnection. The FEA results match well with the experimental results. Further the effect of silicon wafer (cell) thickness on the cell residual stress was also evaluated to show that residual stress in the cell increases linearly with cell thickness reduction. Further it was noted from the simulations that the reduction in cell thickness can be counterbalanced by reducing the interconnect thickness to curtail stress levels. These preliminary results are encouraging and inspire us to evaluate the residual stresses holistically including lamination process with interconnect and solder material plasticity, reduced cell thickness etc. to optimize the interconnection process and topology for a more reliable solar PV technology.

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